

Options and constraints for passive sensor fabrication at CMOS foundries

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With larger and larger areas to be covered for all-silicon trackers and even silicon-based calorimeters, production cost per sensor area and also production turnaround and throughput are becoming important aspects. CMOS foundries have a very large throughput on 8" wafers and may offer very competitive prices, but in turn impose several constraints. The presentation will summarise the pros and cons of CMOS foundries for planar sensor production.

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